

Chao Han

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/3055186/publications.pdf>

Version: 2024-02-01

28
papers

204
citations

1040056

9
h-index

1058476

14
g-index

28
all docs

28
docs citations

28
times ranked

145
citing authors

#	ARTICLE	IF	CITATIONS
1	A Quartz Resonant Ultra-High Pressure Sensor With High Precision and High Stability. IEEE Sensors Journal, 2021, 21, 22553-22561.	4.7	15
2	Research on micro-leverage in monolithic quartz resonant accelerometer. Review of Scientific Instruments, 2021, 92, 025005.	1.3	2
3	High-Stability Quartz Resonant Accelerometer With Micro-Leverages. Journal of Microelectromechanical Systems, 2021, 30, 184-192.	2.5	11
4	The quality factor of quartz DETF for resonant sensors: simulation, analysis and verification. Journal of Micromechanics and Microengineering, 2021, 31, 115001.	2.6	5
5	An integrated packaged resonant accelerometer with temperature compensation. Review of Scientific Instruments, 2020, 91, 105004.	1.3	10
6	Development of V-Shaped Beam on the Shock Resistance and Driving Frequency of Micro Quartz Tuning Forks Resonant Gyroscope. Micromachines, 2020, 11, 1012.	2.9	5
7	Deep Reactive Ion Etching of Z-Cut Alpha Quartz for MEMS Resonant Devices Fabrication. Micromachines, 2020, 11, 724.	2.9	5
8	Research on a Micro-Processing Technology for Fabricating Complex Structures in Single-Crystal Quartz. Micromachines, 2020, 11, 337.	2.9	4
9	A high sensitivity quartz resonant pressure sensor with differential output and self-correction. Review of Scientific Instruments, 2019, 90, 065003.	1.3	8
10	A Novel Resonant Accelerometer Based on Quartz on Silicon (QoS)., 2019, , .		2
11	Analysis and Simulation of the Influence of ω -Beam on the Impact Resistance of Micro Quartz Tuning Gyroscopes. , 2019, , .		0
12	A micro-machined differential resonance accelerometer based on silicon on quartz method. Sensors and Actuators A: Physical, 2017, 253, 1-9.	4.1	9
13	Design of a resonant accelerometer integrated with a diamond like carbon film temperature sensor. , 2017, , .		0
14	A Differential Resonant Accelerometer with Low Cross-Interference and Temperature Drift. Sensors, 2017, 17, 178.	3.8	19
15	Modelling and characterisation of a micromachined resonant pressure sensor with piezoelectric excitation and sensing. Micro and Nano Letters, 2016, 11, 326-331.	1.3	6
16	Research on slide-film damping effect to achieve a high-performance resonant pressure sensor. , 2015, , .		2
17	Design and analysis of a micro pressure sensor with optical fiber. , 2015, , .		0
18	Optical micro-electro-mechanical system pressure sensor based on light intensity modulation. Micro and Nano Letters, 2015, 10, 491-495.	1.3	2

#	ARTICLE	IF	CITATIONS
19	Design and fabrication of a resonant pressure sensor by combination of DETF quartz resonator and silicon diaphragm. <i>Microsystem Technologies</i> , 2015, 21, 631-640.	2.0	21
20	Realization of a micro pressure sensor with high sensitivity and overload by introducing beams and Islands. <i>Microsystem Technologies</i> , 2015, 21, 739-747.	2.0	35
21	A resonant sensor composed of quartz double ended tuning fork and silicon substrate for digital acceleration measurement. <i>Review of Scientific Instruments</i> , 2014, 85, 035004.	1.3	18
22	Feasibility study of a pressure sensor based on double-ended tuning fork quartz resonator. , 2014, , .		4
23	Achievement of a high-sensitive and high-overload sensor based on the bossed-diaphragm structure. , 2014, , .		1
24	A micro resonant acceleration sensor comprising silicon support with temperature isolator and quartz doubled ended tuning fork. , 2014, , .		2
25	Geometry optimization for micro-pressure sensor considering dynamic interference. <i>Review of Scientific Instruments</i> , 2014, 85, 095002.	1.3	9
26	Configuration improvement for micropressure sensor with vibration interference. <i>Micro and Nano Letters</i> , 2014, 9, 680-685.	1.3	4
27	Microresonant accelerometer composed of silicon substrate and quartz double-ended tuning fork with temperature isolator. <i>Micro and Nano Letters</i> , 2014, 9, 664-668.	1.3	4
28	A micro-pressure sensor with high sensitivity and overload resistance. , 2013, , .		1